



In re Application of: TAKESHI MATSUNUMA
 Application No. 10/630,747
 Filed: July 31, 2003
 For: METHOD FOR MANUFACTURING SEMICONDUCTOR DEVICE THROUGH USE OF MASK MATERIAL

U.S. Patent and Trademark Office
 220 20th Street S. Customer Window, Mail Stop Amendment
 Crystal Plaza Two, Lobby, Room 1B03
 Arlington, VA 22202

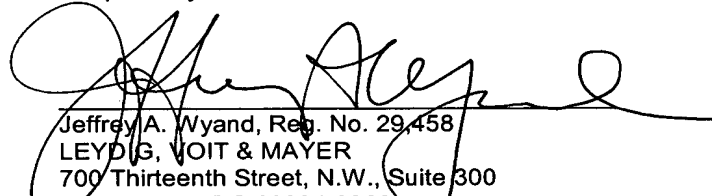
Sir:

- ☐ Small entity status is claimed for this application under 37 CFR 1.27.
- ☒ Petition for an extension of time for the period noted below, as well as for any additional period necessary to render the present submission timely. Please charge Deposit Account No. 12-1216 for the appropriate petition fee.
- ☐ Other:
- ☒ Please charge Deposit Account No. 12-1216 in the total amount indicated below. A duplicate copy of this transmittal sheet is enclosed herewith.

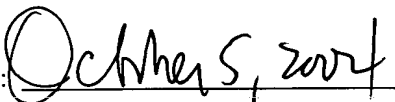
					SMALL ENTITY		OTHER THAN A SMALL ENTITY	
TIME EXTENSION PETITION FEE		none			\$ 0.00		\$ 0.00	
	subtract time extension fee previously paid	none			(\$ 0.00)		(\$ 0.00)	
CLAIM FEE	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR	EXTRA CLAIMS PRESENT	RATE	ADDIT. CLAIM FEE	RATE	ADDIT. CLAIM FEE
TOTAL		MINUS		=0	x 9=	\$	x 18=	\$
INDEPENDENT		MINUS		=0	x 44=	\$	x 88=	\$
<input type="checkbox"/>	FIRST PRESENTATION OF MULTIPLE CLAIM				+ 150=	\$	+ 300=	\$
TOTAL AMOUNT TO BE CHARGED TO DEPOSIT ACCOUNT					TOTAL	\$	TOTAL	\$

- ☒ The Commissioner is hereby authorized to charge any deficiencies in the following fees associated with this communication or credit any overpayment to Deposit Account No. 12-1216.
- ☒ Any filing fees under 37 CFR 1.16 for the presentation of extra claims.
- ☒ Any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,


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Date:





PATENT
Attorney Docket No. 402729

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

TAKESHI MATSUNUMA

Art Unit: 2822

Application No. 10/630,747

Examiner: M. Guerrero

Filed: July 31, 2003

For: METHOD FOR MANUFACTURING
SEMICONDUCTOR DEVICE
THROUGH USE OF MASK
MATERIAL

RESPONSE TO OFFICE ACTION

U.S. Patent and Trademark Office
220 20th Street S. Customer Window, Mail Stop Amendment
Crystal Plaza Two, Lobby, Room 1B03
Arlington, VA 22202

Dear Sir:

In response to the Office Action dated July 12, 2004, please enter the following amendments and consider the following remarks.